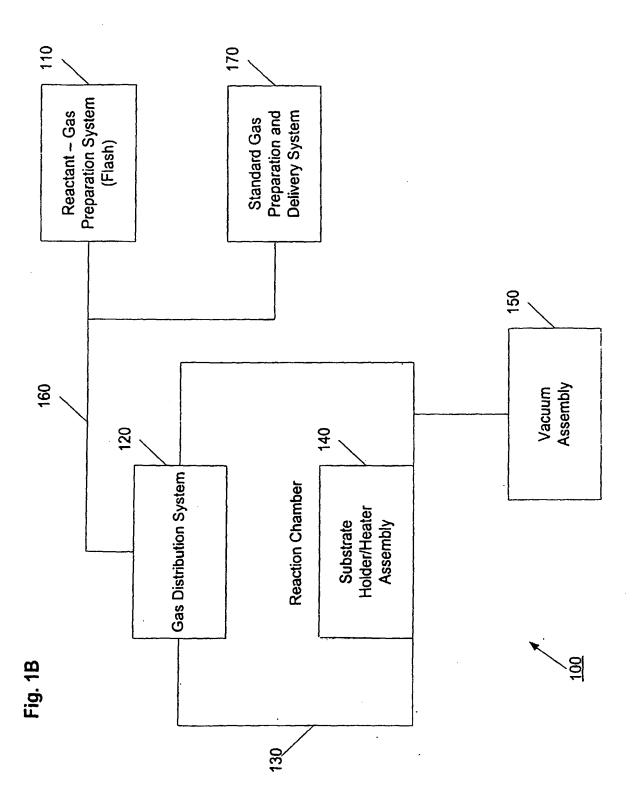
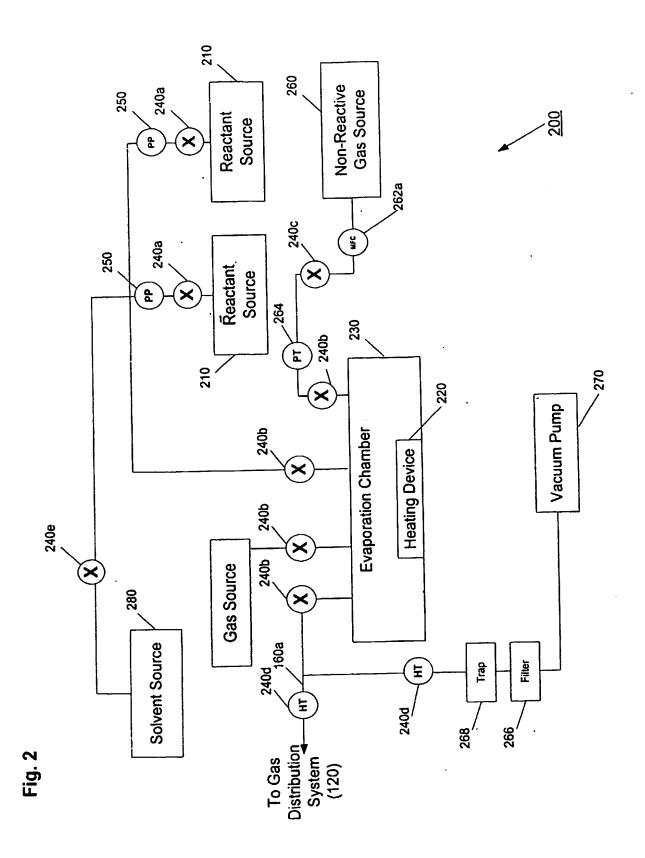


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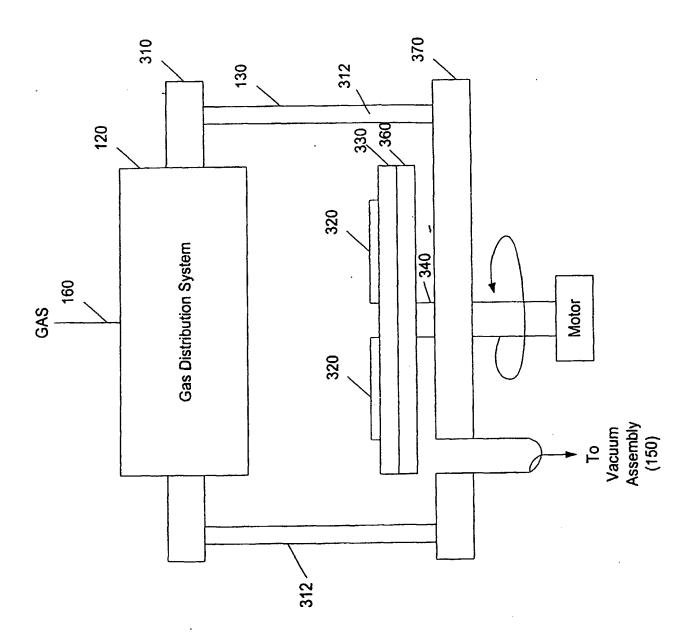
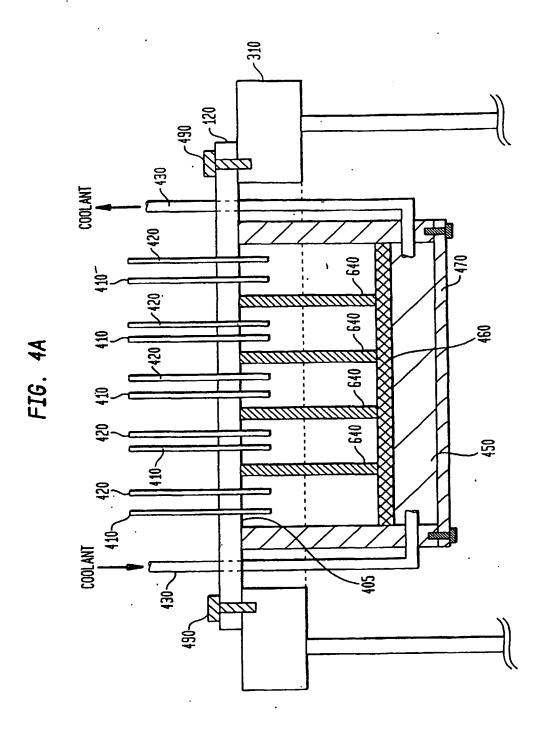
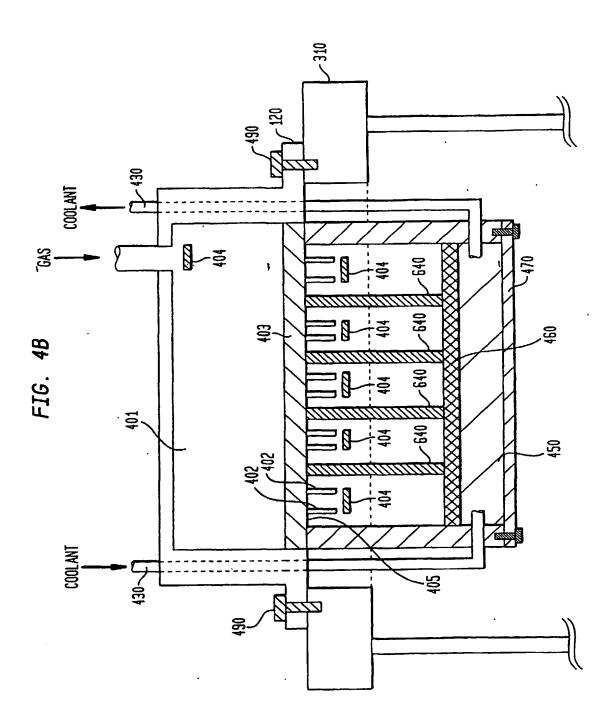


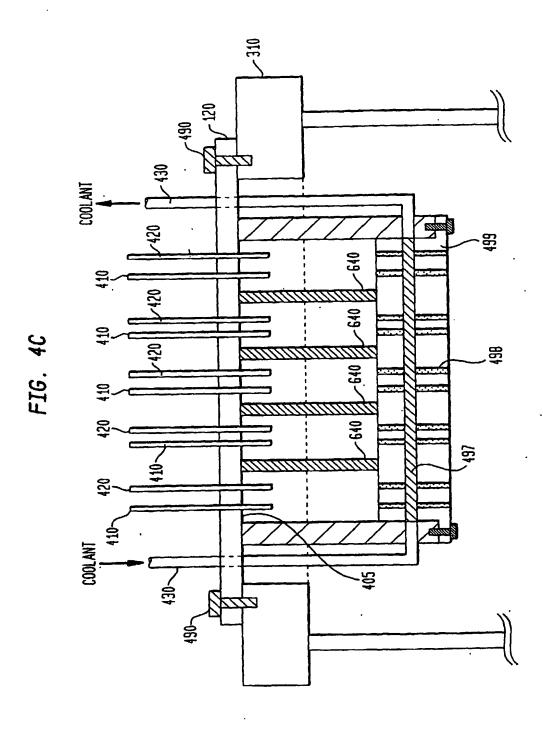
Fig. 3



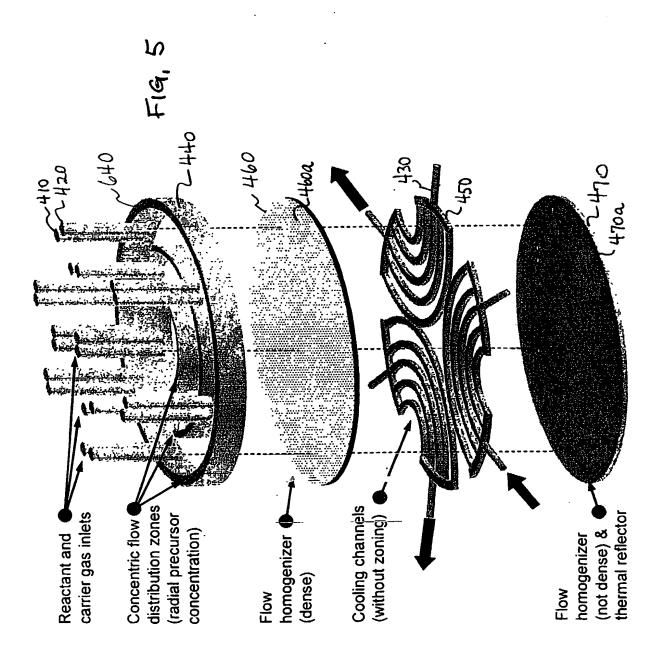
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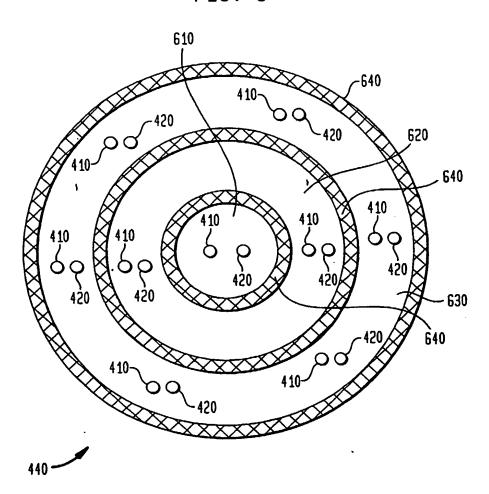


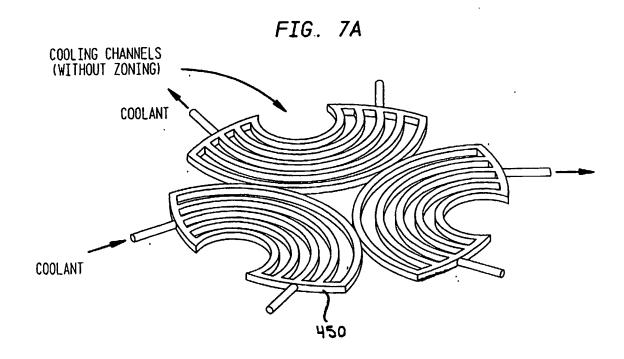
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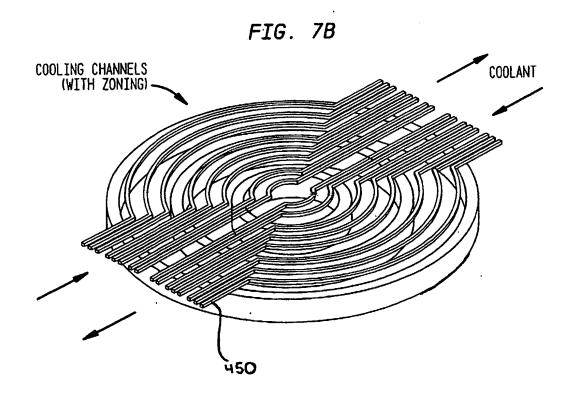


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FIG. 6







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FIG. BA

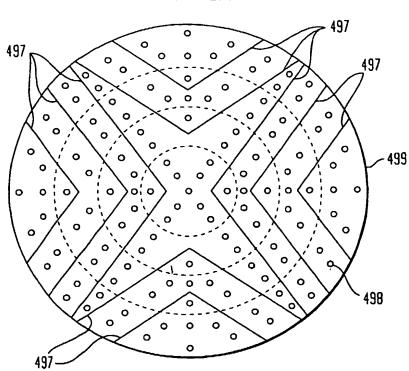
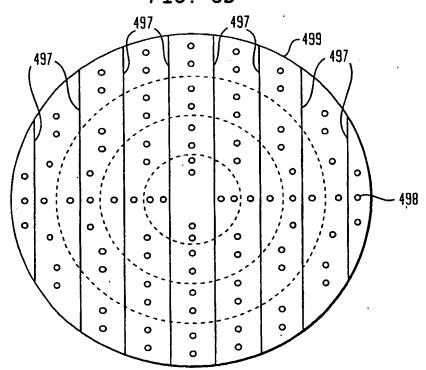
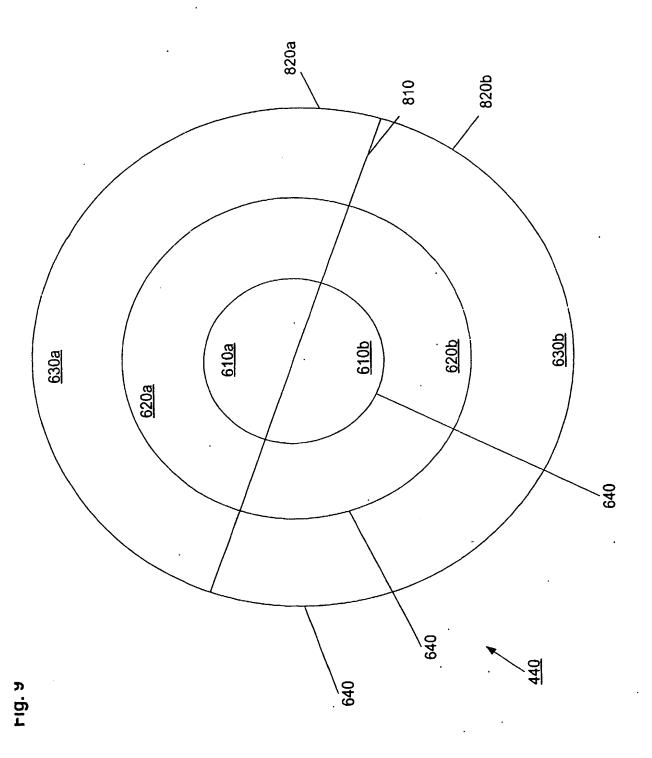


FIG. 8B



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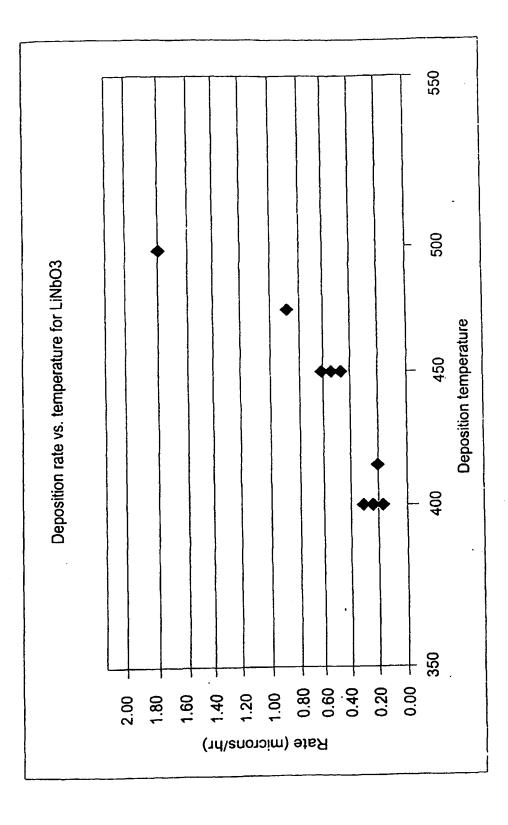
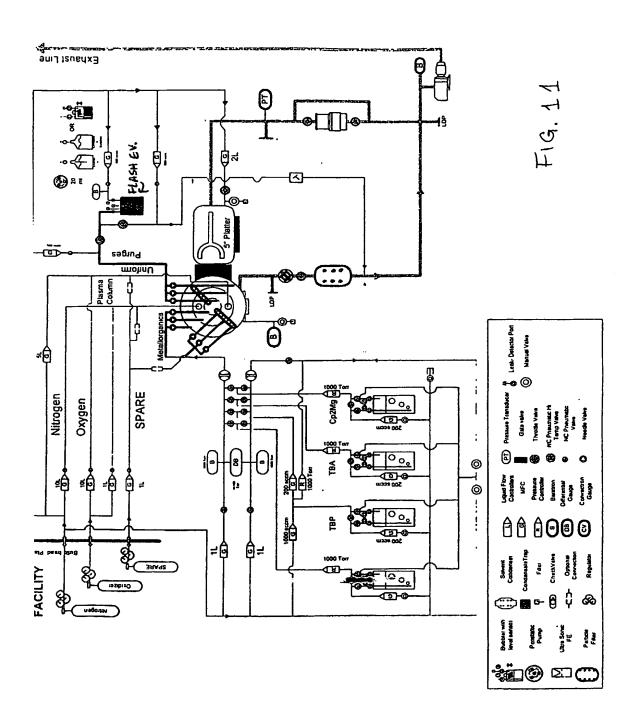


Fig. 10

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## **SUBSTITUTE SHEET (RULE 26)**

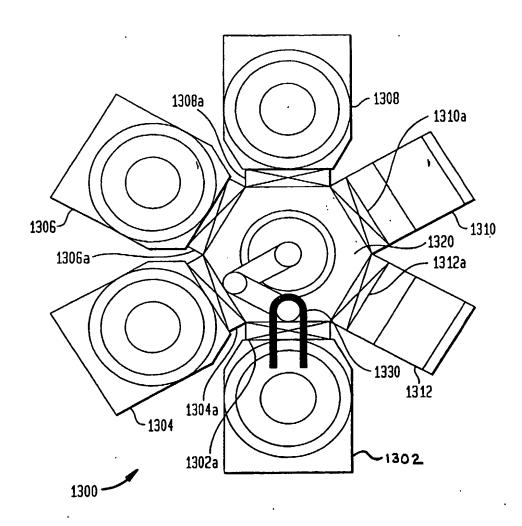
LEGEND സ്ത്ര Baratron on Exhaust Pump
 Flash Evaporator Exhaust Push MFC for ZnO/ pumping system for Ferroelectric Chamber 3. Spare Gas Line with MFC for ZnO/Ferroelect 2. Nitrogen Purged, SS, loadlock with commor 9 Additional Flash Evaporator Assembly for Ferroelectric Chamber 10 Additional Pressure Controllers (PCs) on Metallorganic sources 3 Precusor Condenser in Vent Line for ZnO/ 1 Spare Metallorganic Source for ZnO/ Ferroelectric Chamber emelectric Chamber Femoelectnc Chamber OPTIONS:-Chamber

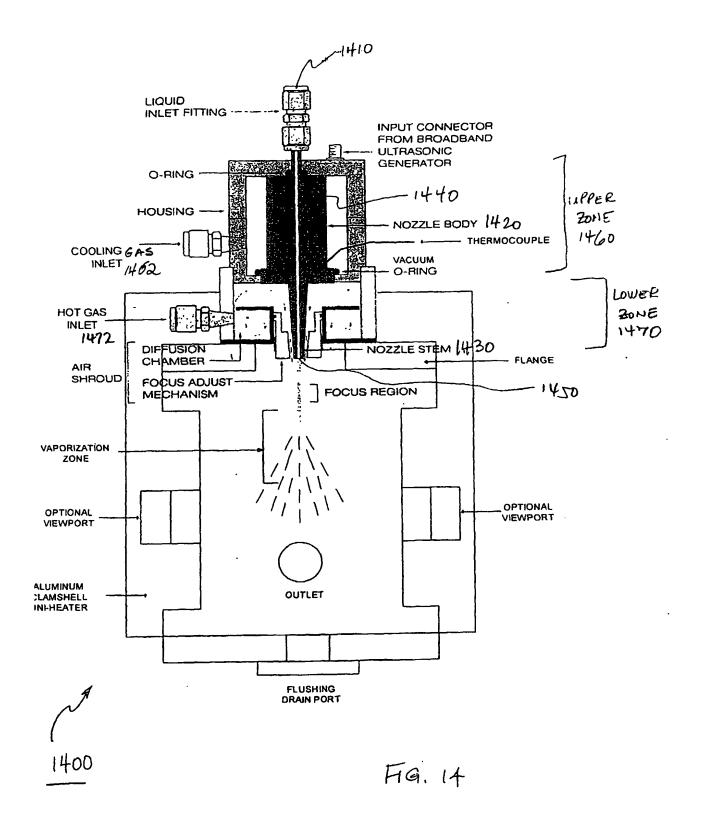
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1200 Flash MOCVD System × 1210 × 1250 Other Film Processing System(s) 1500b 1260 Vacuum System Load Lock × 1110 × 1100 Flash MOCVD System 1000 ×

Fig. 12B

FIG. 13





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